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Patent
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Attorney's Docket No. 015290-500

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of)

S. Y. LI et al.)

Application No.: 09/820,695)

Filed: March 30, 2001)

For: METHOD OF PLASMA ETCHING)
LOW-K DIELECTRIC MATERIALS)
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)

Group Art Unit: 1763

Examiner: A. W. Olsen

Confirmation No.: 4162

AMENDMENT AFTER FINAL REJECTION

Mail Stop AF

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Office Action mailed February 27, 2004, the period for response which has been extended to June 27, 2004, by the Petition for Extension of Time submitted herewith, please amend the above-identified patent application as follows: